

MAD 2025



Precision Measurement of Mechanical Loss & **Thermal Noise Characterisation**

E-TEST: Einstein Telescope EMR Site

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<https://www.pml.uliege.be>

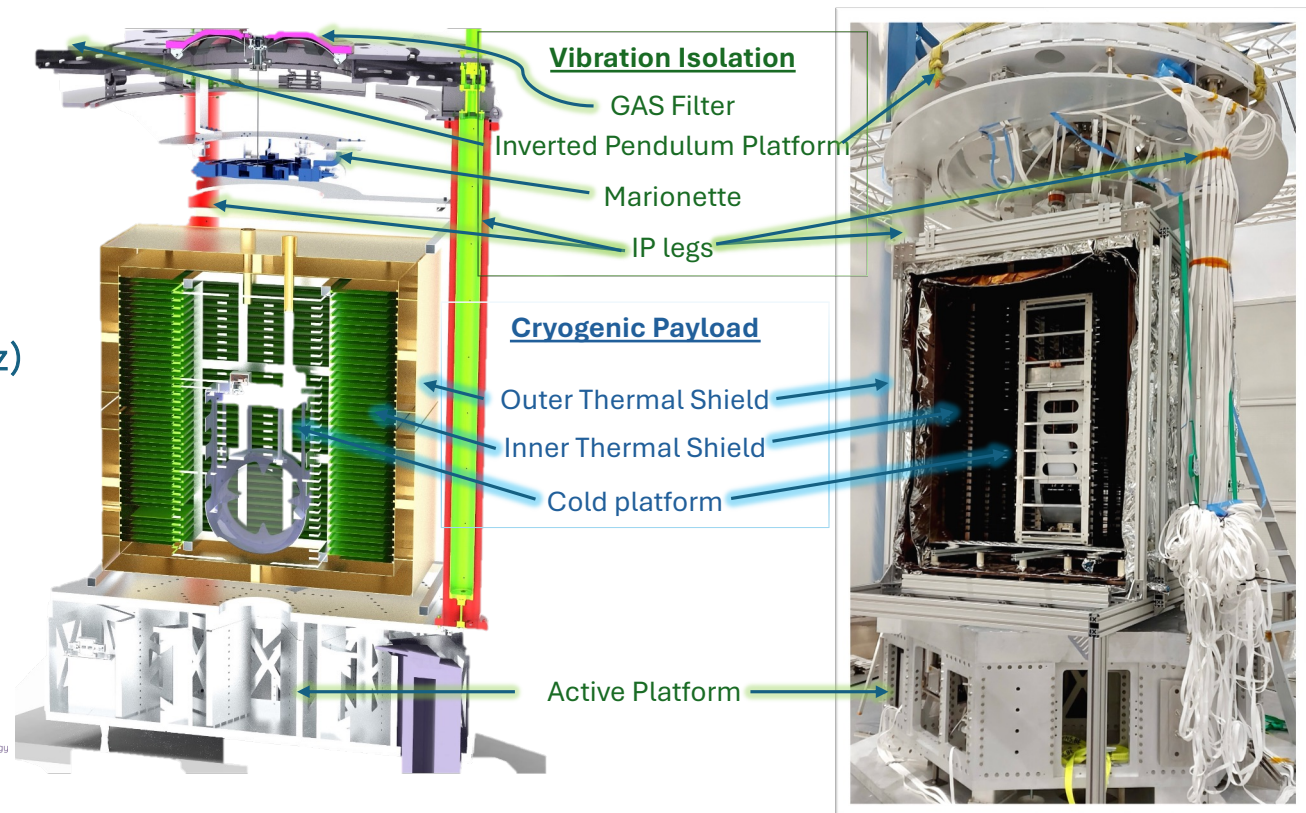


E-TEST Cryogenic Prototype

*From **Concept**, through **Design**, to **Creation!!***

The E-TEST project, supported by Interreg EMR and ET2SME, uses CSL's existing infrastructure to build the facility.

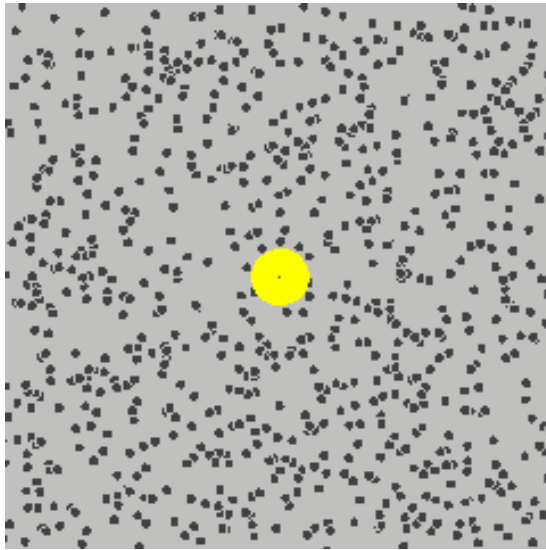
- Isolated at low frequency (0.01-10 Hz)
- Radiative cooling (20 K)
- Large Si mirror (~100 Kg)



Overview: Thermal Noise

Fluctuation-Dissipation Theorem

Relates noise spectrum + system's linear responses to applied perturbations:



Brownian motion of a particle

Power spectrum
of noise

$$x^2(\omega) = \frac{4k_B T k \phi(\omega)}{\omega [(k - m\omega^2)^2 + k^2 \phi^2]}$$

- This equation depends on one unknown, ϕ , the loss angle.
- **Quality Factor** = ϕ^{-1} (dimensionless)

- Thermal Noise Reduction:

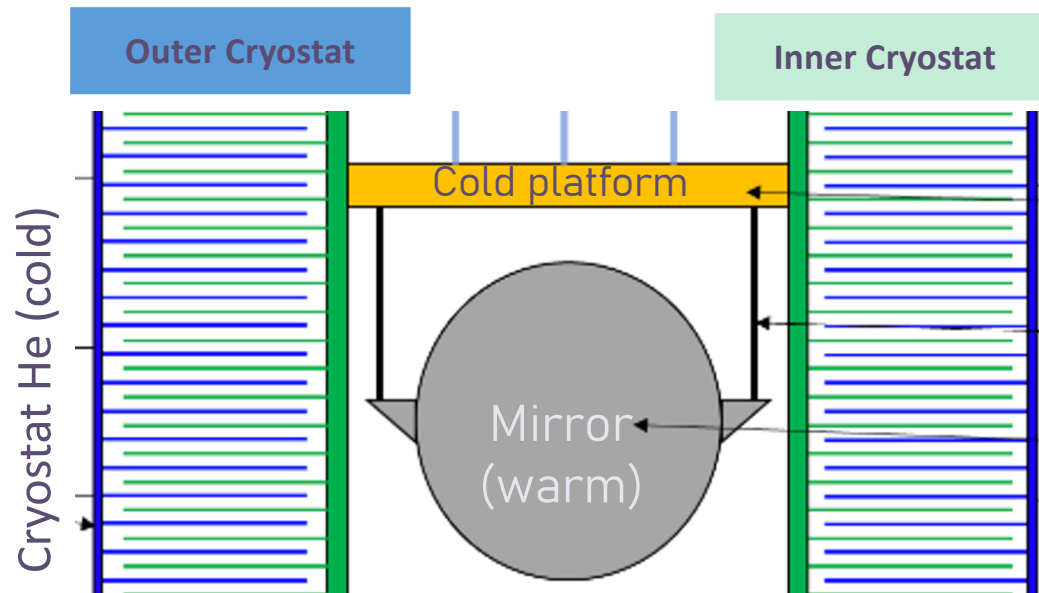
1. **Lower Temperature**
2. **Larger Test Mass**
3. **Increase Q factor** to shift noise above the signal band

- The **mechanical Q-factor** varies with **Temperature**.
- Some materials show a **peak in Q-factor** at certain low temperatures due to changes in **atomic lattice vibrations**.

1. To reach a lower temperature

Radiative Cooling:

- Interlacing fins to increase the radiative heat exchange area (80m² for E-TEST, ~500m² for ET).
- Thermo-mech. topology optimisation of fin geometry with radiation
- Emissivity enhancement at low temperature (coating)



1. To reach a lower temperature

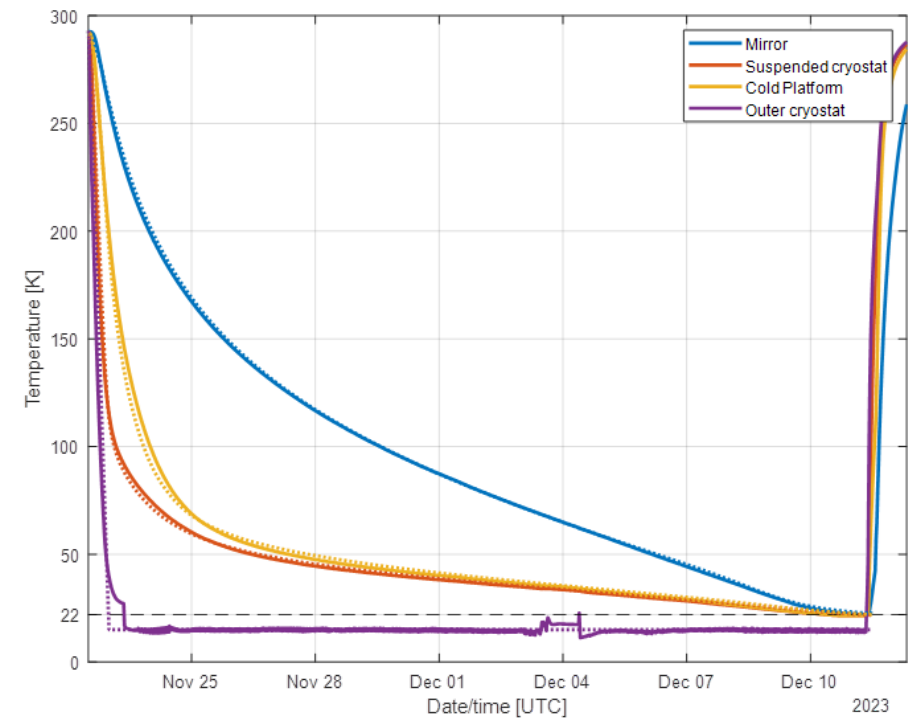
Prototype assembly completed
Nov 2023



First Run (Vacuum)



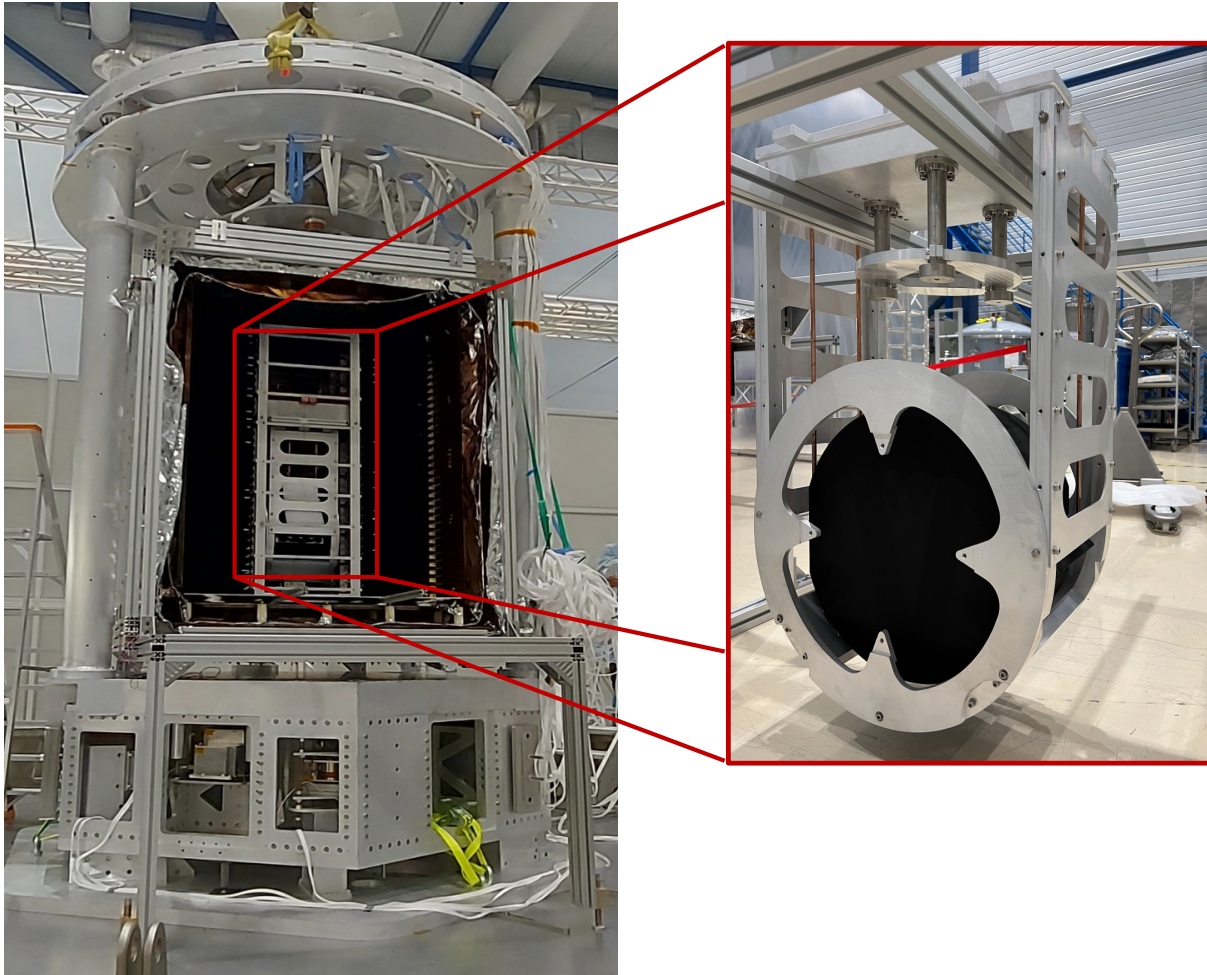
1st run at CSL 2023
22K achieved in 18days !



Note: Dummy Test Mass (Aluminium) was used.

Ref: Jacques Lionel et al.

2. TEST MASS (First Run:2023)



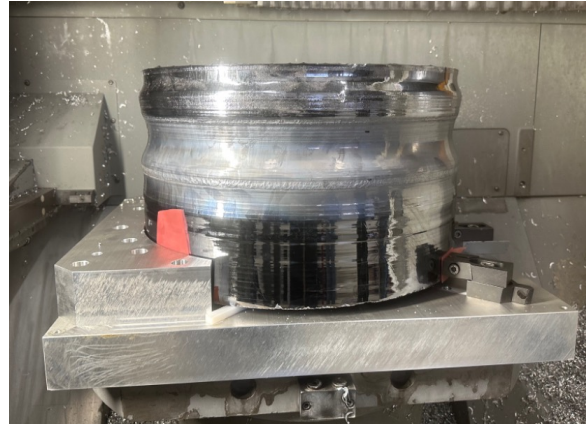
2023: 1st Run: Dummy Test mass

- CuCrZr Suspensions
- Aluminium ears attached to TM
- Black painted finish

2. TEST MASS (Second Run:2025)



- Monocrystalline (Silicon)
Magnetic Czochralski Process
- Diameter: 45 cm
- Mass: 90 kg



Additionally,

1. Mid-tier mass, Cylindrical,
 $\varnothing 4.27$ cm, 3 cm, ~100 g
2. Intermediate mass, Cylindrical,
 $\varnothing 10$ cm, 10 cm, ~1.83 kg

Meeting specific minimum Requirements such as
Roughness <2 nm RMS, Flatness $\lambda/4$,
Parallelism <30 μ rad, ROC ∞ (Flat) etc.

Ref: SINGLE CRYSTAL Silicon database(ET_docs)

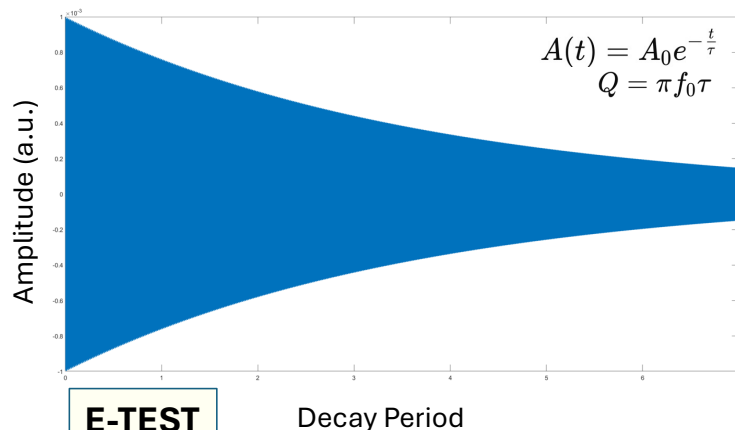
- Diameter: 45 cm
- Thickness ~ 17 cm



3. Mechanical Loss Measurement

Traditional Q- Measurement Method

Monocrystalline Si @ cryo → ultra-high Q, long ring-down!



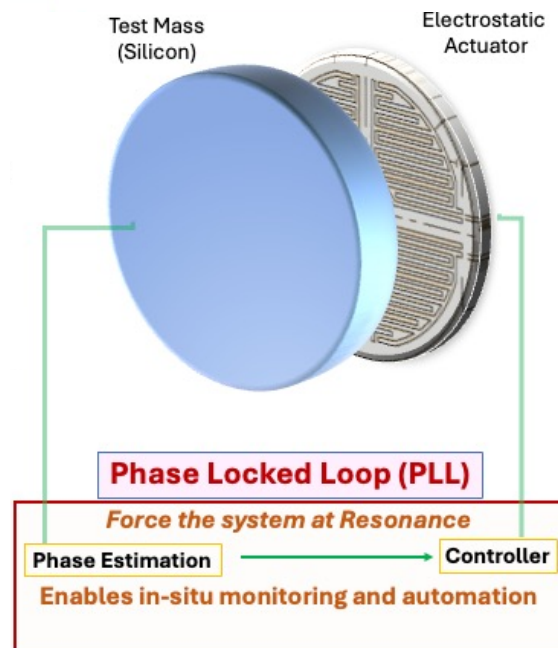
E-TEST

High Q-Factor Silicon Resonator Setup

- Non-Contact Cool Down and **Actuation** (@resonant frequency) of the Test Mass (Si)
- Minimal damping, **Lower Thermal Noise!!**

Why PLL?

- Ring-down too slow for **Silicon**
- Faster, **Real-time tracking of Resonance, Continuous measurement**, no waiting for decay.



Challenges: Non-Contact Method

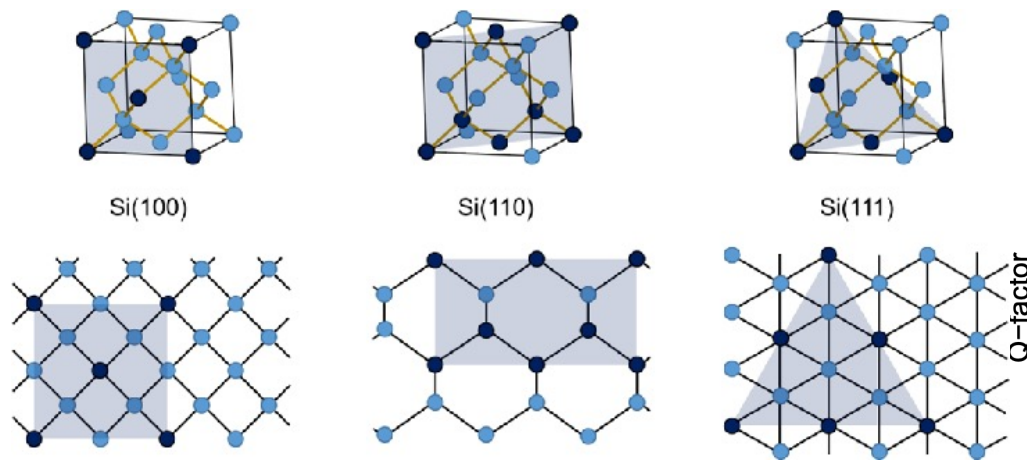
- Development of **ESD** approach and analysis of **Eddy current** generation, unpredictable **electric fringe interactions** due to **semiconducting** properties
- Integration with Phase-Locked Loop (PLL)
- **Compatibility** with **cryogenic** operation

Q v/s Temp relationship !!

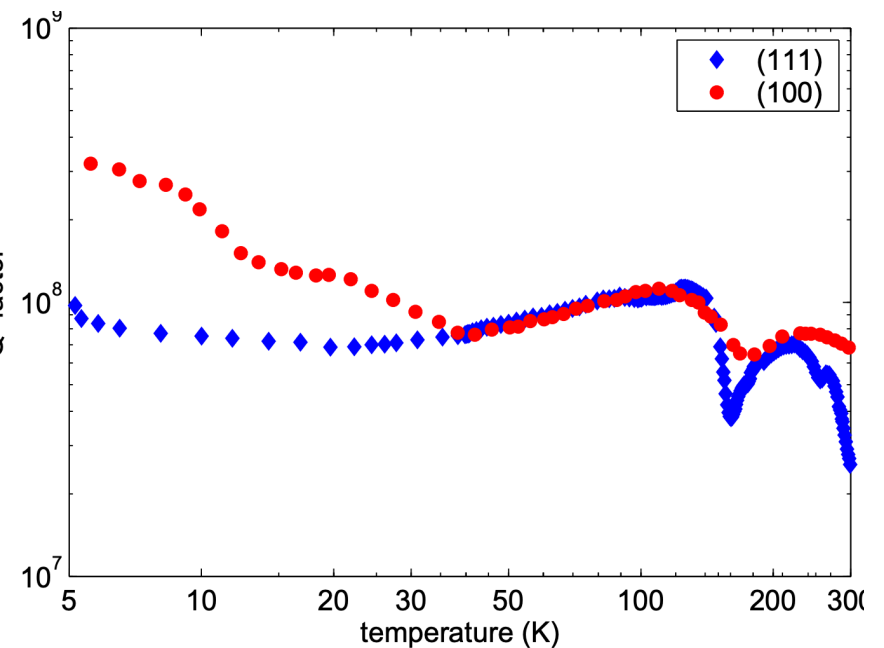
Mechanical Loss Measurement

As Q vs T plot reveals mechanical behaviour of Si Test Mass at **negative CTE (~120K)!!**

- <40 K: Si(100) > Si(111) Q
- Lower phonon scattering
- Reduced dislocation mobility
- Reduced internal friction



Dependency on Crystal orientations



Development of Actuator

Non-contact Method

aLIGO

For 40 kg mass

Max force: 400 μN at 950 V

To achieve the same displacement

For 100 kg Test mass,

1000 μN Force required!!

Resulting Force

$$F_{\text{ESD}} = \alpha(\Delta V)^2,$$

α : ESD actuation coefficient, depends on the separation, material properties, and ESD geometry.

$$\alpha = 2.95 \times 10^{-10} \text{ N/V}^2$$

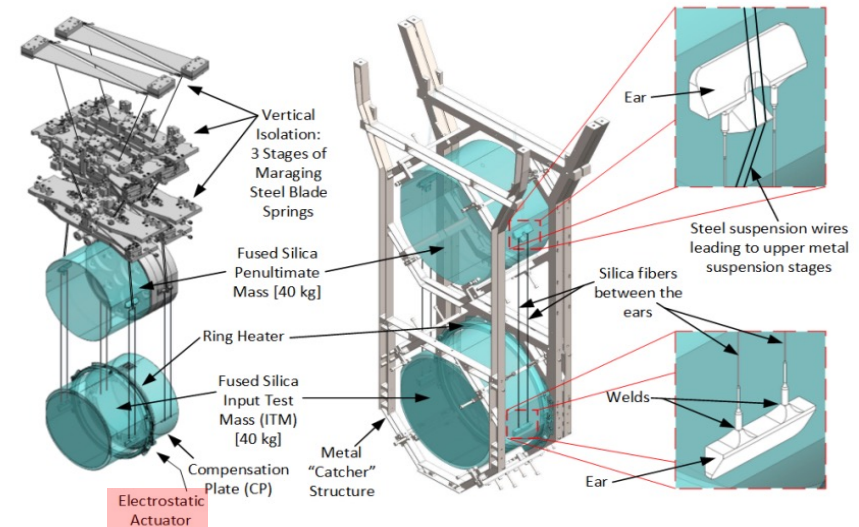


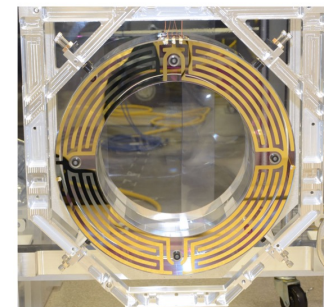
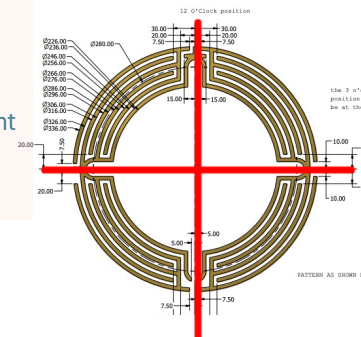
Figure 8 Quadruple pendulum suspension for the Input Test Mass (ITM) optic.

Explored two candidates
(for E-TEST)

1. Photon Actuators (P~150kW)
2. Electrostatic Actuator (V~ 1kV)

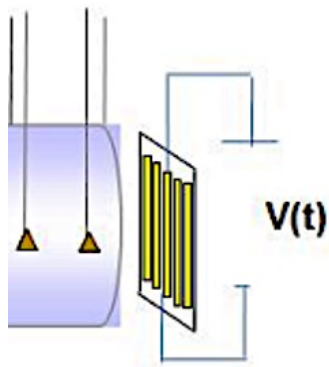
Four Quadrants (DC + AC)

DC bias: creating a static charge environment
AC modulation: oscillating the force



Electrostatic Actuator

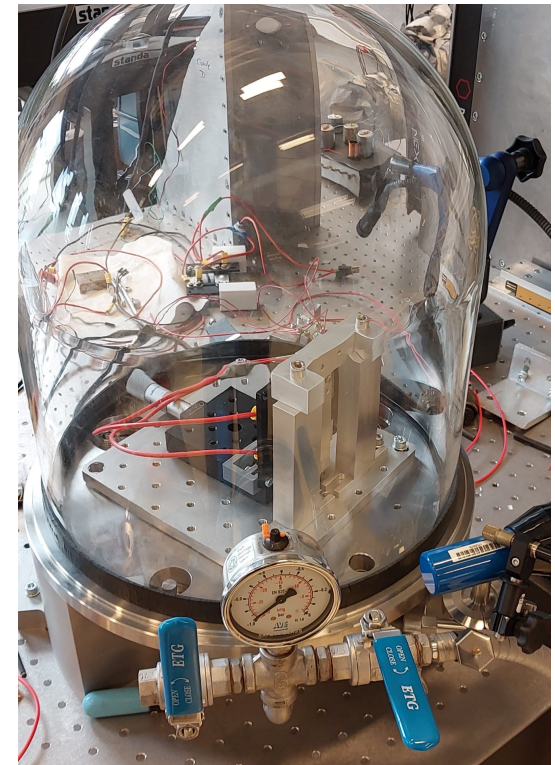
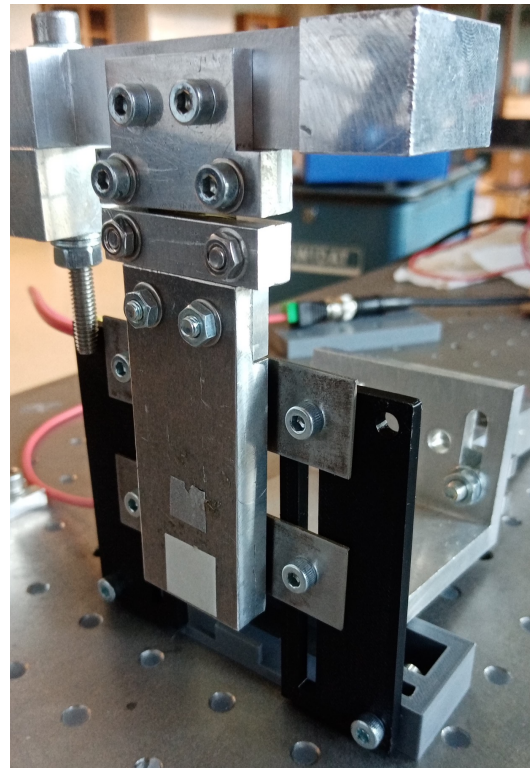
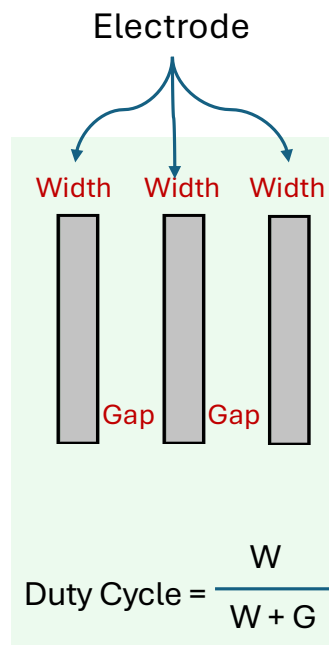
Preliminary Findings



Force depends on:

- Voltage (V)
- Gap distances
- Area of interaction (Fringes)

$$F = \frac{1}{2} \epsilon A E^2, \text{ and } E = \frac{V}{d}$$



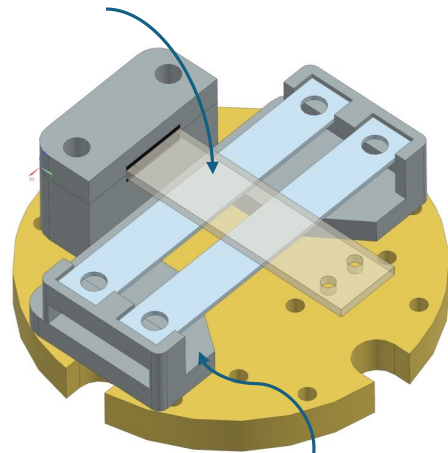
Observations so far:

- DC bias with AC bias produces better results.
- Duty Cycle ~ 50% works better etc.

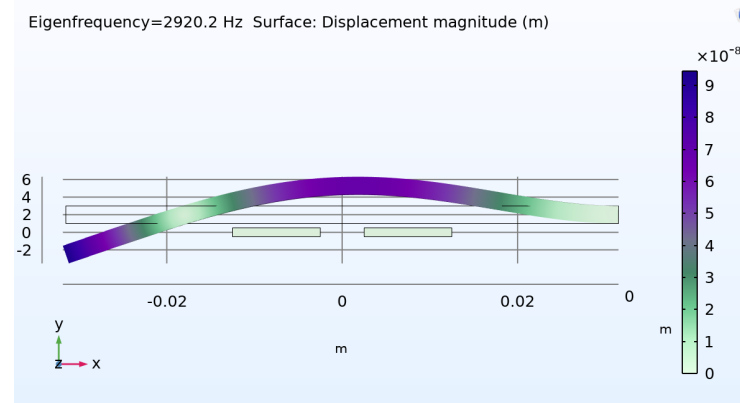
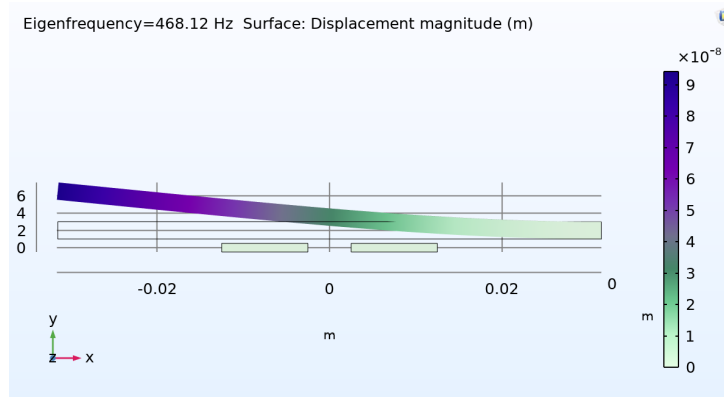
Electrostatic Actuator

In Progress

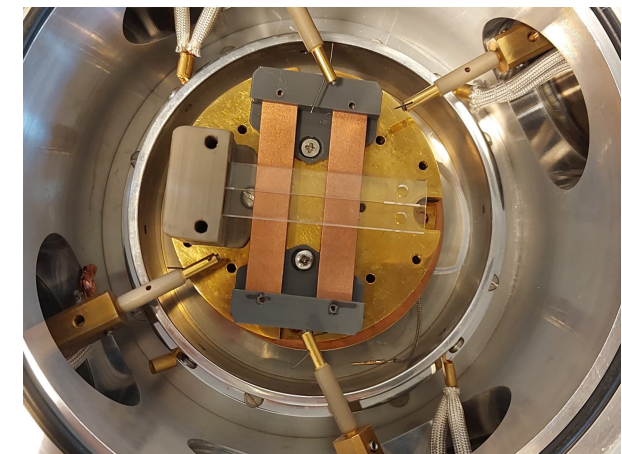
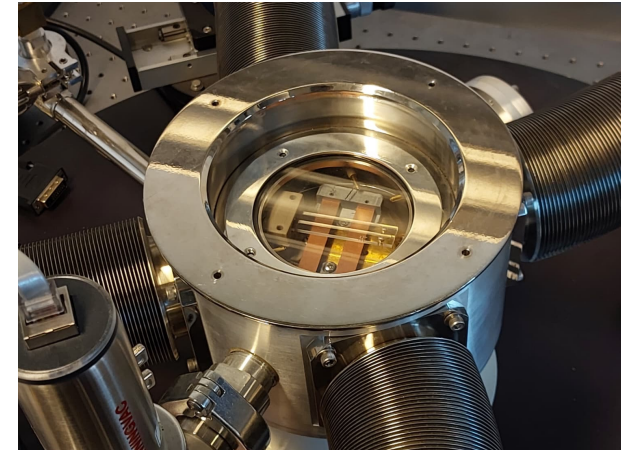
Fused Silica



Electrodes Holder



Multiphysics Simulation (COMSOL)



Experiment

Temperature Measurement (Non- contact Method)

ΔT

Thermo-optic Coefficient

Thermo-Elastic α (dL/dT)

Thermo-Refractive β (dn/dT)

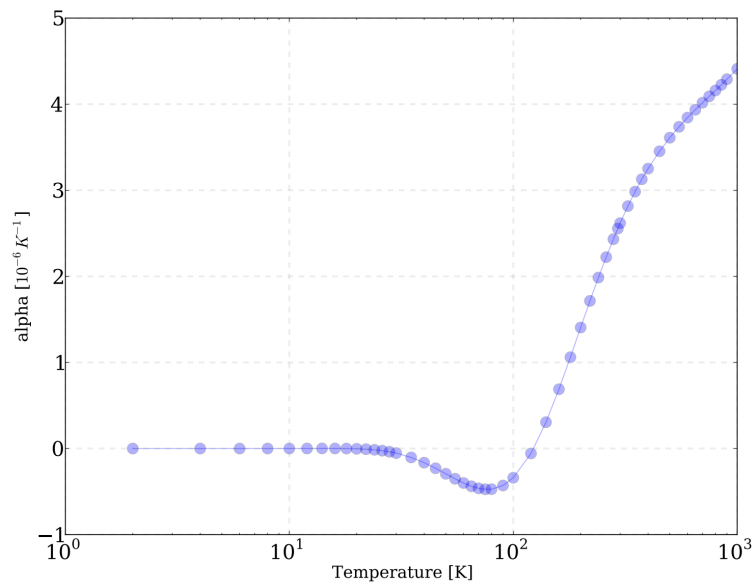


Fig: CTE of Si as function of T

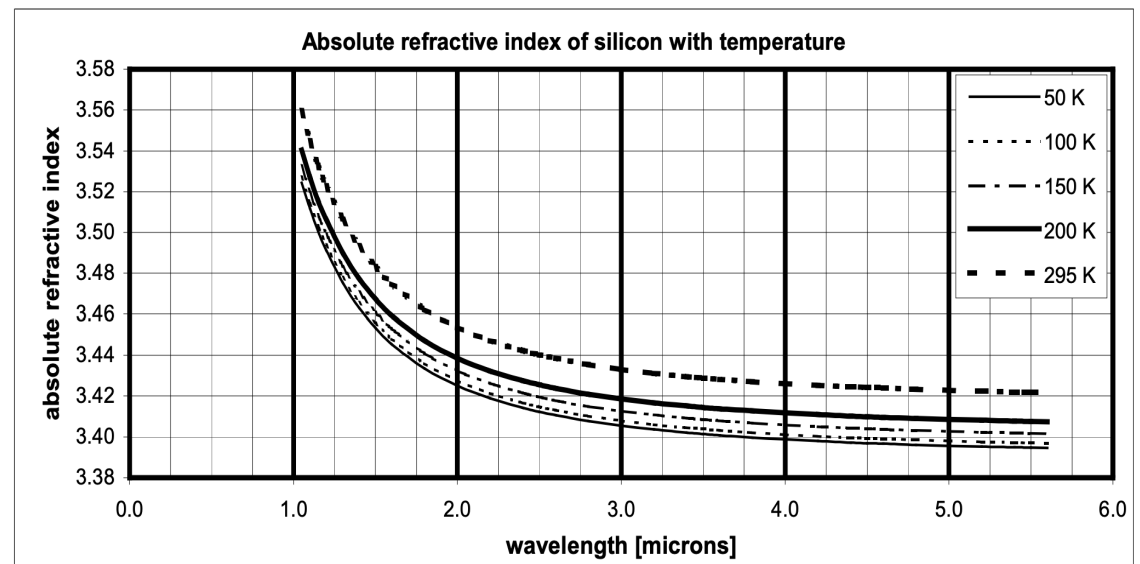


Fig: Measured absolute refractive Index of Silicon as a function of wavelength for selected Temperature

Temperature Measurement (Non- contact Method)

Thermo-refractive Coefficient (β)

i. Silicon (monocrystalline Structure, Semiconductor)

Refractive Index \longrightarrow Electronic structure and polarizability.
High (n) in IR

ii. Heat Generation

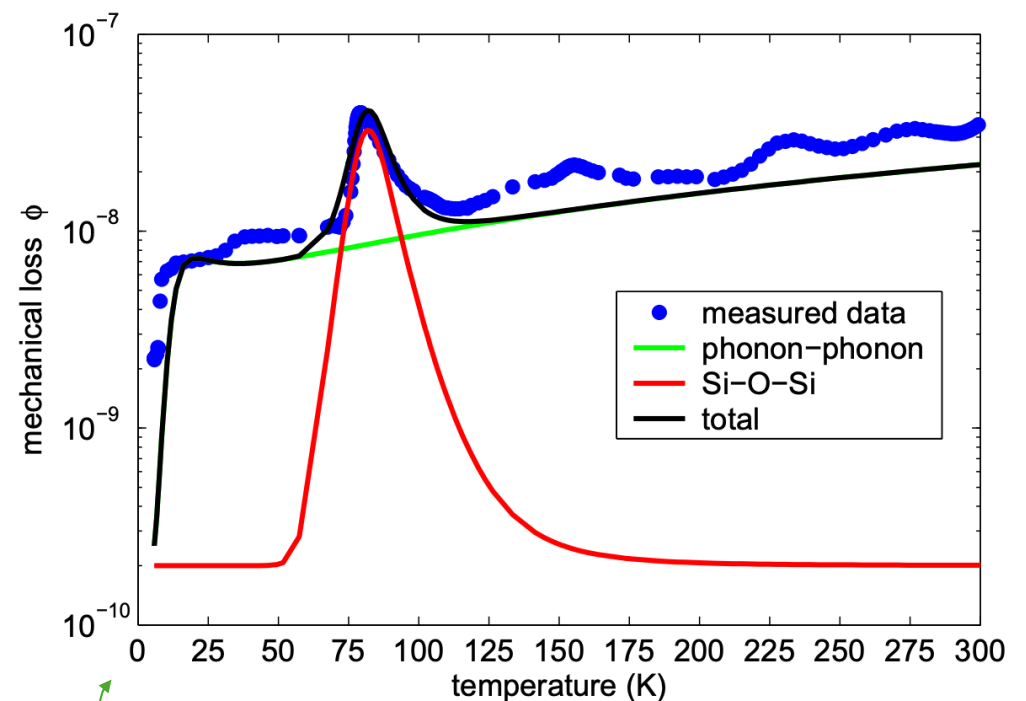
Scattering due to + Laser light Absorption
Free carriers
 (unbound electrons and holes)

$$\alpha_{FC} = \frac{e^2 \lambda^2}{4\pi \epsilon_0 n c^3} \frac{n_c}{m_*^2 \mu}$$

α_{FC} : Free carrier absorption coefficient
 e: Elementary charge
 λ : Wavelength of Light
 ϵ_0 : Vacuum permittivity
 n: Refractive index
 c: Speed of light in vacuum
 n_c : Free carrier concentration
 m_* : Effective mass of the carrier
 μ : Carrier mobility

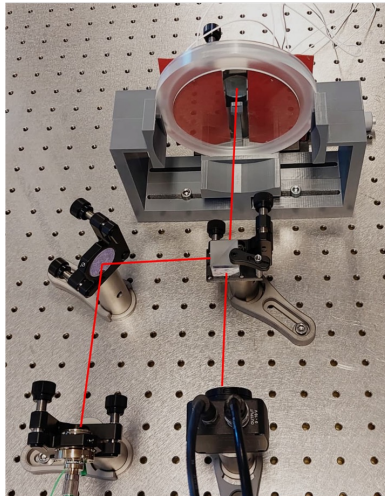
1. Inter-band absorption
2. Two-photon absorption
3. **Free carrier absorption**
 (@NIR/IR wavelength)

Increases the phonon interactions (local heating)

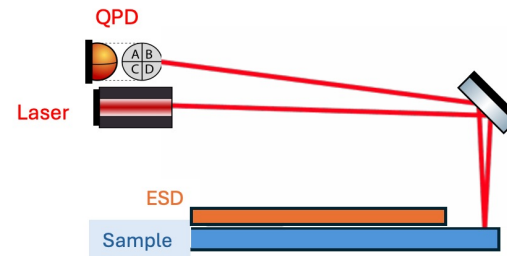


Experimental Framework: Temperature Measurement

Step 01

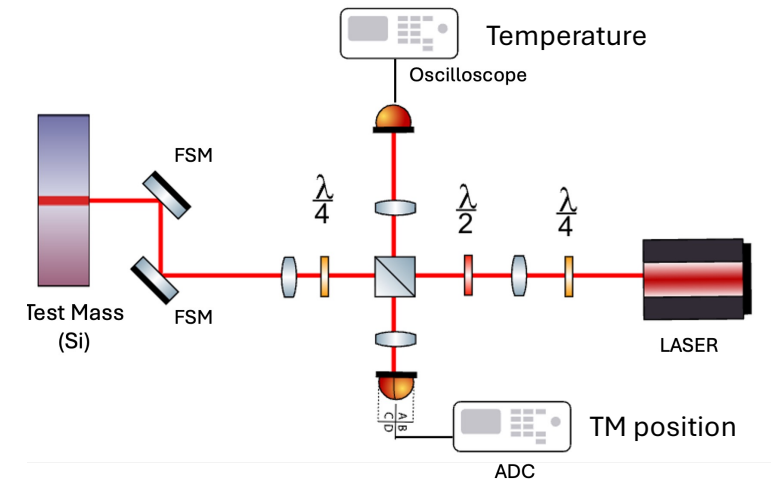


Step 02



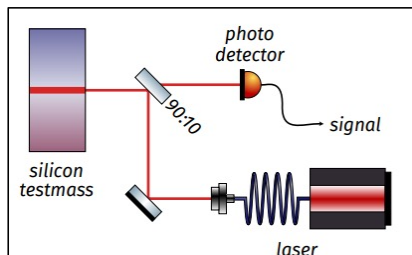
Step 03

@Janis Wöhler

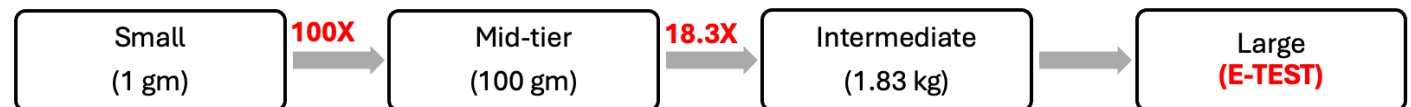


Considerations:

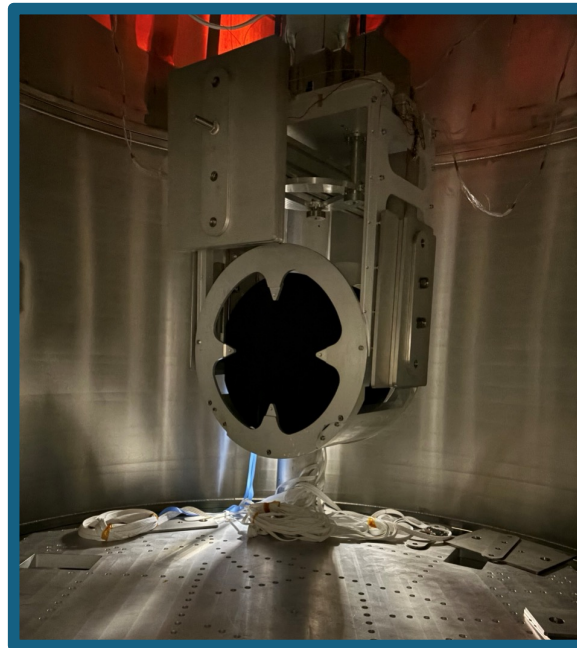
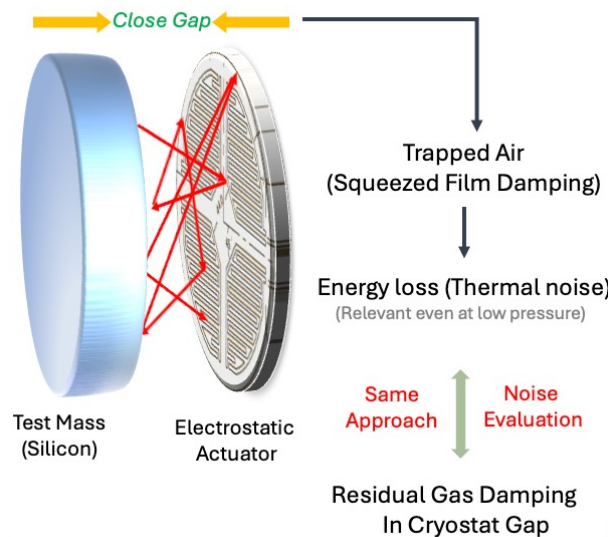
- Effects of ground motion
- LASER (Wavelengths: 1550 nm vs. 2000 nm)
- Scalability



OPL \rightarrow $\Delta T \rightarrow \Delta L$ & $\Delta n \rightarrow$ Fringe shift



Supplementary Studies



Optical Effect

- Laser Absorption Spectra
- Free Carrier Absorption
- Birefringence in Test Mass
- Parametric Instabilities

Charge & Material Interaction

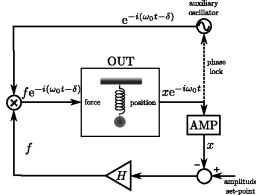
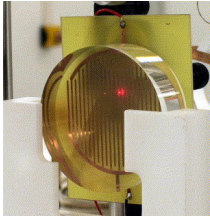
- Charge Induction and Interaction on surfaces
- Reliability of ESD
- Thermal Gradients in the Material
- Effects of Impurities & Orientation on internal Friction

Cryogenic Consideration

- Ice formation during cooldown
- Impact on optical and mechanical performance
- Residual air squeezed damping

Summary

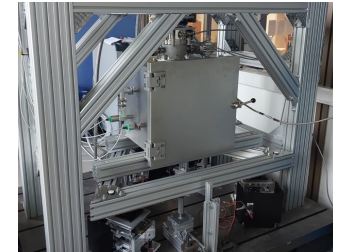
Quality Factor (Q) Measurement



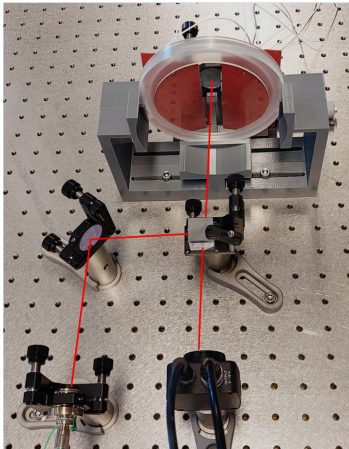
Ongoing

Ongoing

- ☒ Study AC, DC, and AC+DC Current effects
- ☐ ESD designs: Duty Cycle impact on Fringe Generation
- ☐ Fused silica & Silicon samples
- ☐ Apply Phase-Locked Loop
- ☐ Cryogenic testing



Temperature Measurement



Ongoing

- ☐ Fringes $\rightarrow \alpha$ & β (predict thermo-optic coefficients due to ΔOPL)
- ☐ Laser stabilization, Wavelength absorption & Thermal Gradient (1550 nm vs 2000 nm)
- ☐ Final Optical Setup

Integration

- ☐ Real-time Q vs T monitoring

**E-TEST
(2026)**

E-Test: Experimental facility RoadMap

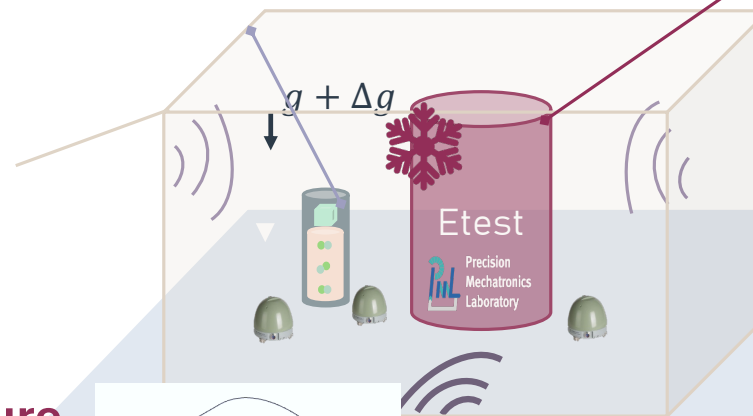
✓ 2023, prototype assembled and tested:

Suspension for 100 kg
Instrumentation developed
Radiative cooling validated

Si suspension + surface treatment
Characterisation
(traction tests + inspection)
ET Fiber project



□ 2025: installation at CSL



□ 2026: R&D @ **Cryogenic Temperature**

- **Active Isolation & control development**
- **Silicon Test Mass Installation & ETFIBER**
- **Inertial sensors development**
- **Newtonian Noise subtraction techniques.**



Si Test Mass





Thank you!!



Additional

Silicon Mechanical Loss Map

